

Crystallographers

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This section is intended to be a series of short paragraphs dealing with the activities of crystallographers, such as their changes of position, promotions, assumption of significant new duties, honours, etc. Items for inclusion, subject to the approval of the Editorial Board, should be sent to the Executive Secretary of the International Union of Crystallography (J. N. King, International Union of Crystallography, 5 Abbey Square, Chester CH1 2HU, England).

Professor **A. Kalman**, Central Research Institute of Chemistry, Hungarian Academy of Sciences, Budapest, Hungary, has been awarded the Golden Medal of Labour Order of Merit by the Hungarian Government in recognition of his outstanding scientific results and activity in serving the international community of crystallographers.

Dr **William Parrish**, IBM Corporation, Research Division, San Jose, California, USA, has been selected to receive the J. D. Hanawalt Award for excellence in

the field of Powder Diffraction. The award is sponsored by the JCPDS – International Centre for Diffraction Data. The presentation of the award is expected to be made at the XIVth General Assembly and International Congress of Crystallography, Perth, Australia, in August 1987.

New Commercial Products

Announcements of new commercial products are published by the Journal of Applied Crystallography free of charge. The descriptions, up to 300 words or the equivalent if a figure is included, should give the price and the manufacturer's full address. Full or partial inclusion is subject to the Editor's approval and to the space available. All correspondence should be sent to the Editor, Professor M. Schlenker, Editor Journal of Applied Crystallography, Laboratoire Louis Néel du CNRS, BP166, F-38042 Grenoble CEDEX, France.

The International Union of Crystallography can assume no responsibility for the accuracy of the claims made. A copy of the version sent to the printer is sent to the company concerned.

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MOS Application Package for DL4600 Series

An **MOS application package** consisting of software and hardware for the DL4600 series DLTS systems is now available from Polaron Equipment. The MOS package allows high-frequency CV measurements for the determination of oxide capacitance, depletion capacitance and doping profiles. MOS DLTS is available for the measurement of surface state densities as well as bulk traps. Zerst measurements can be used both for generation lifetime determination and, in a new 'DLTS' version, to measure directly capacitor hold time as a function of temperature. This new technique is highly sensitive allowing measurements of small devices and the separation of different generation mechanisms, e.g. bulk and space-charge components.

Polaron Equipment Limited, 53–63 Greenhill Crescent, Watford Business Park, Watford, Herts WD1 8QS, England.